



Attorney Docket No. 81328A

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10/8/02  
PATENT  
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OCT - 3 2002  
TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: )  
)  
JOSEPH J. DANKO ) Group Art Unit: 2877  
)  
Serial No:09/579,620 ) Examiner: R. Rosenberger  
)  
Filed: May 26, 2000 )  
)  
For: PARTICLE DETECTION )  
METHOD AND APPARATUS )

Box Fee Amendment  
Commissioner for Patents  
Washington, D.C. 20231

Sir:

AMENDMENT

This communication is in response to an Office Action received on this application dated March 21, 2002. It is respectfully requested that the above-identified application be amended as follows.

IN THE CLAIMS:

Please amend claims 1, 4, 12, 14 and 15 as follows:

1. (Amended) Apparatus for detecting particles on a surface of a semiconductor wafer, said surface having repetitive patterns, the apparatus comprising:

- a. a laser for illuminating an area on said surface with a beam of polarized light,
- b. a first camera,